Contribution ID: 129 Type: Invited Talk

Interference nanolithography based on chalcogenide photoresist

Wednesday, November 6, 2024 8:25 AM (20 minutes)

Type of presence

Presenter: Dr DAN'KO, Viktor (Lashkaryov Institute of Semiconductor Physics (ISP), NAS of Ukraine)

Session Classification: Workshop on Direct Optical Lithography for Advanced Opto- and Microelec-

tronics